1	SCANNING OR POSITIONING ARRANGEMENTS, I.E.,	23	Scanning Tunnelling Microscopy [STM] combined with Atomic
	ARRANGEMENTS FOR ACTIVELY		Force Microscopy [AFM]
	CONTROLLING THE MOVEMENT OR	24	Scanning Near-field Optical
	POSITION OF THE PROBE		Microscopy [SNOM] combined
2	.Coarse scanning or positioning		with Atomic Force Microscopy
3	.Fine scanning or positioning		[AFM]
4	Circuits or algorithms therefor	25	Magnetic Force Microscopy [MFM]
5	MONITORING THE MOVEMENT OR		combined with Atomic Force
J	POSITION OF THE PROBE		Microscopy [AFM]
	RESPONSIVE TO INTERACTION WITH	26	.Scanning Tunnelling Microscopy
	THE SAMPLE		[STM] or apparatus therefor,
6	.By optical means		e.g., STM probes
7	.Self-detecting probes	27	Scanning Tunnelling
8	AUXILIARY MEANS SERVING TO ASSIST		Spectroscopy [STS]
0	OR IMPROVE THE SCANNING PROBE	28	Scanning tunnelling
	TECHNIQUES OR APPARATUS, E.G.,		potentiometry [STP]
	DISPLAY OR DATA PROCESSING	29	Probes, their manufacture, or
	DEVICES		their related instrumentation,
9	.Non-SPM analyzing devices, e.g.,		e.g., holders
,	Scanning Electron Microscope	30	.Scanning Near-Field Optical
	[SEM], spectrometer or optical		Microscopy [SNOM] or apparatus
	microscope		therefor, e.g., SNOM probes
10	.Display or data processing	31	Fluorescence
10	devices	32	Probes, their manufacture, or
11	****	-	their related instrumentation,
12	For error compensation		e.g., holders
12	.Means for establishing or	33	.Atomic Force Microscopy [AFM] or
	regulating a desired environmental condition within		apparatus therefor, e.g., AFM
			probes
13	a sample chamberThermal environment	34	Friction force microscopy
14	Fluid environment	35	Adhesion force microscopy
15		36	Scanning potential microscopy
_	Liquid environment	37	AC mode
16	Vacuum environment	38	Tapping mode
17	.Means for protecting or	39	DC mode
	isolating the interior of a	40	
	sample chamber from external	40	Probes, their manufacture, or
	environmental conditions or		their related instrumentation, e.g., holders
	influences, e.g., vibrations	11	
1.0	or electromagnetic fields	41	Conductive probes
18	.Sample handling device or method	42	Functionalization
19	CALIBRATION ASPECT, E.G.,	43	.Scanning Ion-Conductance
0.0	CALIBRATION OF PROBES		Microscopy [SICM] or apparatus
20	.Calibration standards and	4.4	therefor, e.g., SICM probes
	methods of fabrication thereof	44	.Scanning Capacitance Microscopy
21	PARTICULAR TYPE OF SCANNING PROBE		[SCM] or apparatus therefor,
	MICROSCOPY [SPM] OR	4 -	e.g., SCM probes
	MICROSCOPE; ESSENTIAL	45	Probes, their manufacture, or
	COMPONENTS THEREOF		their instrumentation, e.g.,
22	.Multiple-type SPM, i.e.,	4.6	holders
	involving two or more SPM	46	.Magnetic Force Microscopy [MFM]
	techniques		or apparatus therefor, e.g.,
		4.77	MFM probes
		47	Resonance

## 850 - 2 CLASS 850 SCANNING-PROBE TECHNIQUES OR APPARATUS; APPLICATIONS OF SCANNING-PROBE TECHNIQUES, E.G., SCANNING PROBE MICROSCOPY [SPM]

48	<pre>Probes, their manufacture, or their related instrumentation, e.g., holders</pre>			
49	Probes with magnetic coating			
50	riobes with magnetic coating .Scanning Thermal Microscopy			
50	[SThM] or apparatus therefor,			
	e.g., SThM probes			
51	.Scanning Electro-Chemical			
	Microscopy [SECM] or apparatus			
	therefor, e.g., SECM probes			
52	GENERAL ASPECTS OF SPM PROBES,			
	THEIR MANUFACTURE, OR THEIR			
	RELATED INSTRUMENTATION,			
	INSOFAR AS THEY ARE NOT			
	SPECIALLY ADAPTED TO A SINGLE			
	SPECIFIC SPM TECHNIQUE			
53	.Probe holders			
54	4With compensation for			
	temperature or vibration			
	induced errors			
55	.Probe tip arrays			
56	.Probe characteristics			
57	Shape or taper			
58	Nano-tube tips			
59	Particular materials			
60	.Probe manufacture			
61	Functionalization			
62	APPLICATIONS OF SCANNING-PROBE			
	TECHNIQUES OTHER THAN SPM			
63	SCANNING-PROBE TECHNIQUES OR			
	APPARATUS NOT OTHERWISE			
	PROVIDED FOR			